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APPLICATION NO.	FII	LING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/006,704	1	2/10/2001	Shane J. Trapp	I. Trapp M4065.0369/P369-A 3229	
24998	7590	10/20/2005	EXAMINER		
		RO MORIN & (UMEZ ERONINI, LYNETTE T		
2101 L Street, NW Washington, DC 20037				ART UNIT	PAPER NUMBER
σ.				1765	

DATE MAILED: 10/20/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary		Application No.	Applicant(s)
		10/006,704	TRAPP, SHANE J.
		Examiner	Art Unit
		Lynette T. Umez-Eronini	1765
Period fo	The MAILING DATE of this communication app or Reply	ears on the cover sheet with the c	orrespondence address
WHIC - Exte after - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DAINS ons of time may be available under the provisions of 37 CFR 1.13 SIX (6) MONTHS from the mailing date of this communication. O period for reply is specified above, the maximum statutory period we are to reply within the set or extended period for reply will, by statute, reply received by the Office later than three months after the mailing ed patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be tim rill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONEI	N. nely filed the mailing date of this communication. D (35 U.S.C. § 133).
Status			
1)□ 2a)□ 3)□	Since this application is in condition for allowan	action is non-final. nce except for formal matters, pro	
	closed in accordance with the practice under E	x parte Quayle, 1955 C.D. 11, 45	3 O.G. 213.
4)⊠ 5)□ 6)⊠ 7)□ 8)□ Applicati 9)□ 10)⊠	Claim(s) 26-32,71 and 77 is/are pending in the 4a) Of the above claim(s) is/are withdraw Claim(s) is/are allowed. Claim(s) 26-32,71 and 77 is/are rejected. Claim(s) is/are objected to. Claim(s) are subject to restriction and/or ion Papers The specification is objected to by the Examiner The drawing(s) filed on 10 December 2001 is/are Applicant may not request that any objection to the consequence of the order of the order of the oath or declaration is objected to by the Examiner The oath or declaration is objected to by the Examiner Capital C	vn from consideration. r election requirement. r. re: a)⊠ accepted or b)□ objected or by consideration. drawing(s) be held in abeyance. See on is required if the drawing(s) is objected or security.	e 37 CFR 1.85(a). ected to. See 37 CFR 1.121(d).
Priority ι	under 35 U.S.C. § 119		
a)[Acknowledgment is made of a claim for foreign All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the priority application from the International Bureau See the attached detailed Office action for a list of	s have been received. s have been received in Application ity documents have been receive (PCT Rule 17.2(a)).	on No d in this National Stage
Attachment	t(s) e of References Cited (PTO-892)	4) 🔲 Interview Summary ((PTO.413)
2) 🔲 Notice 3) 🔲 Inform	e of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) r No(s)/Mail Date	Paper No(s)/Mail Da	

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DETAILED ACTION

This communication is response to Applicant's Remarks in Amendment filed 8/3/2005, which were persuasive in showing the prior art of record failed to teach an etchant mixture consisting essentially of at least one fluorocarbon and ammonia. Hence, a new Office Action is presented.

Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.
- 2. Claims 26-32, 71, and 77 are rejected under 35 U.S.C. 102(e) as being anticipated by Smith et al. (US 6,277,733 B1).

Smith teaches, " . . . the wafer would be subjected to a plasma which contains H_2 (deuterium or a hydrogen-containing gas, such as ammonia, can be used in place of H_2) and CF_4 , (or other fluorocarbon, such as C_2F_6 , CHF_3 , CH_2F_2 or other fluorine-containing hydrocarbon, . . ." (column 4, lines 34-38). Since Smith discloses the same composition as claimed by applicants, then using Smith's composition in the same manner as claimed by applicants would inherently result in

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A composition suitable for use in etching an insulative layer formed over a substrate in a semiconductor device, said composition comprising:

a flowing plasma etchant mixture consisting essentially of at least one fluorocarbon and ammonia, wherein said at least one fluorocarbon and ammonia form a reactive mixture, as recited in claim 26.

The above further reads on,

wherein said fluorocarbon is at least one member selected from the group consisting of fluorocarbons, as in claim 27;

wherein said fluorocarbon is at least one member selected from the group consisting of C₄F₈, C₄F₆, C₅F₈, CF₄, C₂F₆, CHF₃, and CH₂F₂, **in claim 28**; and

wherein said fluorocarbon is at least one member selected from the group consisting of CF₄, CHF₃, and CH₂F₂, in claim 29;

wherein said fluorocarbon is at least two members selected from the group consisting of and is a combination of CF₄, CHF₃ and CH₂F₂, **in claim 30**;

wherein said fluorocarbon is a combination of CF₄, CHF₃ and CH₂F₂, in claim 31.

Using Smith's etchants in the same manner as in the claimed invention would result wherein said composition is ineffective to remove side wall spacers of a gate formed over said substrate, in claim 32;

The above aforementioned also reads on,

A composition suitable for use in etching an insulative layer formed over a substrate in a semiconductor device, said composition consisting of:

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a plasma etchant mixture consisting of CF₄, at least one other fluorocarbon, and NH₃. Since Smith discloses the same composition as claimed by applicants, then using Smith's composition in the same manner as claimed by applicants would result wherein said CF₄, at least one other fluorocarbon and NH₃, form a reactive mixture, as recited **in claim 71**.

The said aforementioned further reads on,

A composition suitable for use in etching an insulative layer formed over a substrate in a semiconductor device, said composition consisting of: a gaseous etchant mixture, consisting of at least one fluorocarbon and ammonia. Since Smith discloses the same composition as claimed by applicants, then using Smith's composition in the same manner as claimed by applicants would result wherein said at least one fluorocarbon and ammonia NH₃, form a reactive mixture, as recited **in claim 71**.

Claim Rejections - 35 USC § 102

3. Claim 77 is rejected under 35 U.S.C. 102(b) as being anticipated by Fumio et al. (JP 54054578).

Fumio teaches, "... using the plasma of mixed gases of CF₄ and NH₃ at the time of etching the PSG film and SiO₂ film on Si substrates" (Abstract), which reads on,

A composition suitable for use in etching an insulative layer formed over a substrate in a semiconductor device, said composition consisting of:

A gaseous etchant mixture consisting of at least one fluorocarbon and ammonia, wherein said at least one fluorocarbon and ammonia form a reactive mixture.

Response to Arguments

4. Applicant's arguments, see Remark (pages 4-6 in Amendment), filed 8/3/2005,

with respect to claims 26-32, 71, and 77 have been fully considered and are persuasive.

The 102(b) rejection of the said claims 26-32, 71, and 77 has been withdrawn.

Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Lynette T. Umez-Eronini whose telephone number is

571-272-1470. The examiner is normally unavailable on the First Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Nadine Norton can be reached on 571-272-1465. The fax phone number

for the organization where this application or proceeding is assigned is 571-273-8300.

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IN EXAMINER

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October 13, 2005